

Title (en)

METHOD FOR PRODUCING A MICROMECHANICAL DEVICE AND A MICROMECHANICAL DEVICE

Title (de)

VERFAHREN ZUR HERSTELLUNG EINER MIKROMECHANISCHEN VORRICHTUNG UND VORRICHTUNG

Title (fr)

PROCEDE POUR REALISER UN DISPOSITIF MICROMECHANIQUE ET DISPOSITIF

Publication

EP 1594799 A2 20051116 (DE)

Application

EP 03815817 A 20030925

Priority

- DE 0303194 W 20030925
- DE 10305442 A 20030211

Abstract (en)

[origin: WO2004071941A2] The invention relates to a method for producing a micromechanical device and to corresponding micromechanical device consisting of a substrate material (10), a membrane (20) and a hollow space (30) formed in the region of membrane (21) between said substrate and membrane. According to said invention holes (40) are embodied first and foremost in the membrane (20) during a first etching stage and afterwards, the hollow space is produced during a second etching stage.

IPC 1-7

B81B 3/00

IPC 8 full level

B81B 3/00 (2006.01)

CPC (source: EP US)

B81C 1/00047 (2013.01 - EP US); **B81C 1/0069** (2013.01 - EP US); **B81B 2203/0127** (2013.01 - EP US); **B81C 2201/0109** (2013.01 - EP US)

Citation (search report)

See references of WO 2004071941A2

Designated contracting state (EPC)

DE FR IT

DOCDB simple family (publication)

WO 2004071941 A2 20040826; **WO 2004071941 A3 20041223**; DE 10305442 A1 20040819; EP 1594799 A2 20051116; JP 2006513047 A 20060420; US 2006226114 A1 20061012

DOCDB simple family (application)

DE 0303194 W 20030925; DE 10305442 A 20030211; EP 03815817 A 20030925; JP 2004568081 A 20030925; US 54335703 A 20030925